Docket No.: W&B-INF-701

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**Applicant** 

Harald Richter et al.

Applic. No. Filed

09/917,549 July 27, 2001

Title

Method of Processing Organic Antireflection Layers

## INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner of Patents and Trademarks, Washington, D.C. 20231

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

U. S. Patent 5,910,453 (Gupta et al.), dated June 8, 1999;

Patent Abstracts of Japan 11 150 115 A (Beivich et al.), dated June 2, 1999;

Tanabe: "Reactive Ion Etching of AL Alloy Films in a Rotating Magnetic Field", Jpn. J. Appl. Phys., Vol. 32, Part 1, No. 2, dated February 1993, pp. 747-752;

German Examination Report, dated July 27, 2000;

If no translation of pertinent portions of any foreign language patents or publications mentioned above is included with the aforementioned copies of those applications, patents and/or publications, it is because no existing translation is readily available to the applicant.

Respectfully submitted,

For Applicants

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Date: October 16, 2001

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